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<b>INFORMATION DISCLOSURE STATEMENT</b>							
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<b>U.S. PATENT DOCUMENTS</b>							
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EP	/	Tamura et al, "Oriented Crystal Growth of Si on SiO <sub>2</sub> Patterns by Pulse Ruby Laser Annealing" Proceedings of the 12 <sup>th</sup> Conference on Solid State Devices, Tokyo (1980), pp. 43-48					
EP	/	H. R. Wenk et al. "Texture Analysis of Polycrystalline Silicon Films" J. Appl. Phys. 67 (1) 1/1/1990 pp. 572-574					
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